Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A substrate transfer apparatus for a component mounting machine, for transferring a substrate into a mounting process ~~(8)~~ in which components are mounted onto the substrate and transferring the substrate from said mounting process ~~(8)~~, comprising:

a mounting-waiting process ~~(7)~~ for making the substrate to be transferred into the mounting process ~~(8)~~ wait before the mounting process ~~(8)~~; and

a substrate discharge-waiting process ~~(9)~~ for making the substrate after being transferred from the mounting process ~~(8)~~ wait before a following process, wherein

transfer of an unmounted substrate ~~(3)~~ from said mounting-waiting process ~~(7)~~ to the mounting process ~~(8)~~ and transfer of a mounted substrate ~~(2)~~ for which mounting has been done in the mounting process ~~(8)~~ from the mounting process ~~(8)~~ to the substrate discharge-waiting process ~~(9)~~ are performed simultaneously,

characterized in that detecting means ~~(6)~~ are provided for detecting that a plurality of substrates have been transferred into the substrate discharge-waiting process ~~(9)~~ as part of the same transfer.

2. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 1, wherein the detecting

means includes: a substrate-arrival detecting sensor (5c) for detecting the mounted substrate (2) transferred into the substrate discharge-waiting process (9); and a substrate-continuity detecting sensor (6), provided upstream of the substrate-arrival detecting sensor (5c), for detecting an unmounted substrate (3) being transferred at the same time as the mounted substrate (2).

3. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 2, wherein the substrate-continuity detecting sensor (6) is arranged at a position that satisfies $X < XS < 2X$, where a distance from the substrate-arrival detecting sensor (5c) to the substrate-continuity detecting sensor (6) is XS and a substrate dimension in the substrate transfer direction is X.

4. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 3, wherein the substrate-continuity detecting sensor (6) is arranged to be movable to the position that satisfies $X < XS < 2X$.

5. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 3, wherein the substrate-continuity detecting sensor (6) is constructed to be automatically movable to the position that satisfies $X < XS < 2X$, in accordance with the substrate dimension X in the substrate transfer direction.

6. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 1, wherein the detecting

means includes: a substrate-arrival detecting sensor (~~5c~~) for detecting the mounted substrate (~~2~~) transferred into the substrate discharge-waiting process (~~9~~); and a plurality of substrate-continuity detecting sensors (~~6a, 6b, 6c~~), provided upstream of the substrate-arrival detecting sensor (~~5c~~) at different positions in a substrate transfer direction from one another, for detecting an unmounted substrate (~~3~~) being transferred at the same time as the mounted substrate (~~2~~).

7. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 6, wherein the substrate-continuity detecting sensors (~~6a, 6b, 6c~~) detect an unmounted substrate (~~3~~) by a substrate-detection state of one (~~6b~~) of the plurality of substrate-continuity detecting sensors (~~6a, 6b, 6c~~) that is located at a position satisfying $X < XS < 2X$, where a distance from the substrate-arrival detecting sensor (~~5c~~) to the one substrate-continuity detecting sensor (~~6b~~) is XS and a substrate dimension in the substrate transfer direction is X.

8. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 6, wherein the substrate transfer apparatus includes a minimum required number of the substrate-continuity detecting sensors (~~6a, 6b, 6c~~) by arranging N sensors that satisfy $2^N \times P\_min > P\_max$ at positions determined by $2^n \times P\_min\ 2$ ($n = 1, 2, ..., N$) from a minimum substrate size (P_min) and a maximum substrate size (P_max) in the substrate transfer direction, respectively, for which the electronic component mounting machine (~~1~~) is intended.

9. (Currently Amended) The substrate transfer apparatus for a component mounting machine according to claim 7, wherein the substrate transfer apparatus includes a minimum required number of the substrate-continuity detecting sensors ~~(6a, 6b, 6c)~~ by arranging N sensors that satisfy $2^N \times P\_min > P\_max$ at positions determined by $2^n \times P\_min\ 2$ (n = 1, 2, ..., N) from a minimum substrate size (P_min) and a maximum substrate size (P_max) in the substrate transfer direction, respectively, for which the electronic component mounting machine ~~(1)~~ is intended.